

Notice of References Cited	Application/Control No. 09/592,750	Applicant(s)/Patent Under Reexamination TOYAMA, KENTARO	
	Examiner Ryan J. Miller	Art Unit 2621	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-6,502,082 B1	12-2002	Toyama et al.	706/16
	C	US-5,864,630 A	01-1999	Cosatto et al.	382/103
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	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Koller et al. "Using learning for approximation in stochastic processes", Proceedings of the Fifteenth International Conference on Machine Learning (ICML-98), Madison, Wisconsin, July 1998, pgs. 287-295.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.